

Dielectric Etch

**Configured for 300mm wafer size MFG Date:
2007**

EQUIPMENT DETAILS:

Tool is configured with 3 chamber

Standard Specifications

Software Revision: Linux 6.75 Rev 000-VSTD6.75a

Lot Stability Dummy SW: Software for running lot stability wafer.

OEE WPH Software: SW only for OEE throughput upgrade.

Wafer Size: Diameter 300+/- 0.20mm(SEMI M1.15), Notch

Carrier: FOUP (Comply with SEMI E47.1 (25wafers))

Inter Face: 4 carrier stage (Continuous flow operation) with Semi compliant MENV and FIMS assemblies

Online Connection: GEM / CIM GJG (Hardware Interface : Ethernet 100Base-Tx)

**Utility Box: Regulator : Air/AR2500(SMC), N2/SQ-420E(VERIFLO),
He/SQMICRO(VERIFLO)**

Utility Box: Manual Valve : OGD20V-6RM-K/OGD10V-4RM-K(CKD)

Utility Box: Pressure Gauge : Bourdon Gauge

Loader Mod Corrosion Prevent: SUS Parts, Ball screw & Liner guide : PTFE Coating

Load Lock Pressure Monitor: Pressure Switch : VSA100A (INFICON)

Load Lock Pressure Monitor: Pirani gauge : TTR211S LEYBOLD)

Load Lock Pressure Monitor: CM : 626A01TDE (MKS)

Maintenance Monitor: 2 (Flat Panel Display Touch Screen Type)

Water Leak Detector: 4 (LM;1, each PS;1)

Signal Tower: Red / White / Green / Blue

EMO: 7(Front:2, Rear:5)

Cable Length: 20m (Interconnection), 19 (Top RF cables),20m(Btm RF cables)

Inter Locks: External (When the I/L signal is received from Factory, gas valves are closed)

Fittings: No Brass Fittings

Supporting Remote Units

Chiller: Daikin UBRPD5A-2T2

*** stopped production**

Coolant: Lower:FC3283, Upper:FC40

Chiller Hose: BRINE HOSE Top/Btm : 18/19M

Handy Maintenance Controller: LCD DISPLAY UT3-TLN21-A

RF Generator TOP: AGA-50B2

RF Matcher TOP: AMN-50B2

RF Generator Bottom: WGA-50E

Matching Controller: WMN-50H2(2MHZ/5KW)

Pen Record Box: N/A

Loader Module: SELME2112ZS2-AR5(M)

BX80-071026-15

LOAD PORT: SELOP12F25-30B-14

BX80-070965-14

DRIVE UNIT: SBX92102926

BX80-070974-21

READER OPTICAL: None

Carrier ID Reader: N/A

APC: 10 INCH (250MM)

Hardware Configuration

Proc Chbr 1,2,3: SCCM Oxide; Y203 Coating

Chamber hardware: FCC

Endpoint type: SE2000ii

ESC type: Ceramics ESCwith STD Vpp

Focus ring: 3.4mm

Thunderwall He Gas Inlet: Ceramic Thunderwall with Ceramic pusher pins.

Polished focus ring: N/A

FC lower insulator: INSULATOR,LOWER (RE)

3D10-250542-11"

Magnet Shield: O

Oring for Chbr Body-Depos: Armorcrystal

Chemraz SC657"

CEL Body ASSY: Upper electrode constant temperature control

TMP: FT-3301

(MITSUBISHI)"

TMP Back Pressure Monitor: 51A11TGA2BA003 (MKS)

Dry Pump: ESR100WN:Ebara

Final Valve, Heater: Valve; AGD21V-6RM-GWL4 (CKD)

Filter: Filter; CEP-TM_HL-VR-03PB (Toshiba Ceramic)

APC: 10 INCH (250MM)

Pressure Monitor: C/M (Process Monitor) : 627BRETDD2P (MKS), 45deg, 30Pa

Pressure Monitor: C/M (Self Check) : 627B11TDC2P (MKS), 45deg, 1330Pa

Pressure Monitor: B.A. Gauge (CM Calibration) : BPG400 (INFICON), 2.0x10⁻⁵ ~ 0.1Pa

Pressure Monitor: ATM Switch : 41A13DGA2AA040 (MKS)

Pressure Monitor: Pressure Switch : 51A11TGA2BA010 (MKS), H2/fluoro gas

Gas Box Configuration

Gas Line 1: (01) NONE / F300

Gas Line 2: (02) CH2F2 / F80

Gas Line 3: (03) C4F8 / F122

Gas Line 4: (04) C4F6 / F180

Gas Line 5: (05) Ar / F2000

Gas Line 6: (06) O2 / F1300

Gas Line 7: (07) O2 / F65

Gas Line 8: (08) CO / F200

Gas Line 9: (09) CHF3 / F200

Gas Line 10: (10) CF4 / F300

Gas Line 11: (11) NONE / F50

Gas Line 12: (12) NONE / F500

Gas Line 13: (13) C4F6 / F39

Gas Line 14: (14) CHF3 / F50

Gas Line 15: (15) Ar / F110

Gas Line 16: (16) O2 / F10

Purge: One line serves up to 16 lines per box

Filter: CNF1004USG4(Nihon Pall)

GTMF3200F4A-VM4(Nihon Pall)

Regulator: N2-Purge: 12-1A21IGS2W(TESCOM)
Filter (N2): CNF1004USG4(Nihon Pall)
GTMF3200F4A-VM4(Nihon Pall)
Valve: Primary Side(Utility - FCS) :
Mega mini(FUJIKIN)
Valve: Secondary Side(FCS - PC) :
Mega One (FUJIKIN)
Piping: Dual piping at gas line from gas box to Final Valve & exhaust through gas box
Gas Leak Detection Port: 5 Ports (6.35mm, Swagelok type)
Final Pressure Switch: 51A (MKS)
Pressure Gauge: Bourdon Gauge(0.2Mpa)
(GAS1: Digital Gauge)
Pressure Gauge: Bourdon Gauge(0.4Mpa)
SP3 Gas Line Connection: Single Line Drop
GBROR: None

Process Kit Configuration

WINDOW, SHIELD DEPO(DRM2) QRTZ: WINDOW, SHIELD DEPO (DRM2) QUARTZ
(ES1D05-400022-14)
WINDOW DEPO SAF0.5(DRM2) SAPP: WINDOW DEPO SAF0.5(DRM2) SAPPHIRE
(ES1D10-406499-11)
SHIELD, UP 300MM RING-Qrtz: SHIELD, UPPER 300MM RING - Quartz (ES3D05-
200094-12)
Insulator, ESC Enclosure (COC): Insulator, ESC Enclosure (COC) - Quartz (ES3D05-300142-
13)
Cover Ring, 360- L (M) - Qrtz: Cover Ring, 360- L (M) - Quartz (ES3D05-300243-11)
RING, BTM SHIELD Y-AL, SE: RING, BTM SHIELD Y-AL, SE (ES3D10-100844-11)
PLATE,EXHAUST Y-AL, SE: PLATE,EXHAUST Y-AL, SE (ES3D10-100845-11)
SHUTTER,BTM TYPE Y-AL, SE: SHUTTER, BTM TYPE Y-AL, SE (ES3D10-101152-13)
SHIELD,DEPO: SHIELD,DEPO (ES3D10-100910-12)
Focus Rg, 360-302-COC: Focus Rg, 360-302-COC (ES3D10-250007-11)
Insultr, lwr T32-R6-BL-NC: Insulator, lower T32-BI-NC
WINDOW,DEPO CLP: WINDOW,DEPO CLP/Y2O3-100P(N) (ES3D10-350344-12)
SCREW PIN LOCK, Cerazol: Ceramic (ES3D10-404821-11)
Si Upper Electrode: Si Upper Electrode (ES3D10-302020-11)
CEL ASSY: CEL ASSY (ES3D87-003411-14)
ESC ASSY: ESC ASSY (with ceramic pusher pins) (ES3D87-052854-11)

